

## **Amendment to the Specification**

**The Paragraph beginning at Page 1, lines 6-14, is to be deleted and replaced with the Paragraph as follows:**

### **CO-PENDING APPLICATIONS**

Various methods, systems and apparatus relating to the present invention are disclosed in the following co-pending applications filed by the applicant or assignee of the present invention simultaneously with the present application:

10/753419	7162324	7162325	10/753486	7146236	10/753499
6997698	10/753332	10/753643	10/753440	10/753421	10/753420
10/753487					

The disclosures of these co-pending applications are incorporated herein by cross-reference.

**The Paragraph beginning at Page 1, lines 14-25, through to Page 6, lines 1-16, is to be deleted and replaced with the Paragraph as follows:**

The preferred printhead is a Micro Electro Mechanical System (MEMS) type printhead in which a material is ejected from a chamber under the control of a movable element. Reference is made to the following patent specifications that disclose numerous such MEMS type printheads or printhead components:

6227652	6213588	6213589	6231163	6247795	6394581
6244691	6257704	6416168	6220694	6257705	6247794
6234610	6247793	6264306	6241342	6247792	6264307
6254220	6234611	6302528	6283582	6239821	6338547
6247796	6557977	6390603	6362843	6293653	6312107
6227653	6234609	6238040	6188415	6227654	6209989
6247791	6336710	6217153	6416167	6243113	6283581
6247790	6260953	6267469	6273544	6309048	6420196
6443558	6439689	6378989	6848181	6634735	6623101
6406129	6505916	6457809	6550895	6457812	6428133
6390605	6322195	6612110	6480089	6460778	6305788
6426014	6364453	6457795	6315399	6338548	6540319
6328431	6328425	6991320	6595624	6417757	7095309
6854825	6623106	6672707	6588885	7075677	6428139
6575549	6425971	6383833	6652071	6793323	6659590
6676245	6464332	6478406	6439693	6502306	6428142
6390591	7018016	6328417	6322194	6382779	6629745
6565193	6609786	6609787	6439908	6684503	6755509
6692108	6672709	7086718	6672710	6669334	7152958
6824246	6669333	6820967	6736489	6719406	10/728804
7128400	7108355	6991322	10/728790	7118197	10/728970

10/728784      10/728783      7077493      6962402      10/728803      7147308  
10/728779

Such MEMS type printheads may utilize different ejection mechanisms for different ejectable materials while other MEMS printheads may utilize different movable shutters to allow different materials to be ejected under oscillating pressure. It is to be understood that whilst MEMS type printheads are preferred, other types of printhead may be used, such as thermal inkjet printheads or piezoelectric printheads.

**The Paragraph beginning at Page 1, lines 15-16, is to be amended as follows:**

Figure [[14]] 15 is a diagram showing remapping of layer groups after the second failure but before all data has been transferred.